

ICO20: MEMS, MOEMS, And NEMS 21-26 August, 2005, Changchun, China

by Masayoshi Esashi ; Zhaoying Zhou; International Commission for Optics; United States; Society of Photo-optical Instrumentation Engineers

UPC 9780819460639 - Ico20: Mems, Moems, and Nems - UPC . ICMIT 2005: Control Systems And Robotics 20-23 September, 2005 . . ?ICO20 :MEMS, MOEMS, and NEMS : 21-26 August 2005, Changchun, China ?ICO20 :illumination, radiation, and color technologies : 21-26 August, 2005, ????????????? - ??????? - ????? ICO20 : MEMS, MOEMS, and NEMS [electronic resource] : 21-26 August 2005, Changchun, China. Language: English. Imprint: Bellingham, Wash. : SPIE, c2006 Title, ICO20: MEMS, MOEMS, and NEMS : 21-26 August, 2005, Changchun, China Volume 6032 of Proceedings of SPIE--the International Society for Optical . ICO20: MEMS, MOEMS, and NEMS : 21-26 August, 2005 . ICO20 : (MEMS, MOEMS, and NEMS) (21-26 August 2005, Changchun, China) MEMS, MOEMS, and NEMS. Conference, Changchun , CHINE (2005) , vol. CiNii Books ?? - International Commission for Optics 6026. ???1?. 5. ICO20 : MEMS, MOEMS, and NEMS : 21-26 August, 2005, Changchun, China. 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